August 27, 2008

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: OKAJIMA, et al.

Serial No.: 10/581,557

June 2, 2006 Filed:

Title: Method for Processing Substrate, Apparatus for Processing Substrate,

Method for Conveying Substrate and Mechanism for Conveying

Substrate

Art Unit: 3724

Examiner: Peterson, K.

Conf. No.: 6205

RESPONSE

Mail Stop: Amendment (No Fee) Commissioner For Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This is in response to the Office Action mailed July 31, 2008, in connection with the above-identified application.

In response to the restriction requirement in the outstanding office action, applicants elect the invention of Group I, including claims 1 – 5, 22 and 23, characterized by the Examiner as being drawn to a special feature of a method of processing a substrate.

Examination of the elected invention in due course is requested.

To the extent necessary, applicants petition for an extension of time under 37 CFR 1.136. Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of Antonelli,

Terry, Stout & Kraus, LLP, Deposit Account No. 01-2135 (Case: 1343.46164X00), and please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

/Alan E. Schiavelli/ Alan E. Schiavelli Registration No. 32,087

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